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MSE 104, LEC. 1 Final Exam Spring 2022 June 7 3-6pm		NAME:			
All work must be clearly shown with proper		UCLA ID:			
un	its in the final answer to receive full credit.		1 (20 pts)		
Please write on front of page only – extra paper will be provided if you need it.			2 (10 pts)		
			3 (10 pts)		
			4 (14 pts)		
<u>Problem 1 (20 pt)</u>			5 (12 pts)		
<u>Problem 1 (20 pt)</u>			6 (14 pts)		
T	Which of the following polymers may be recycled?	(2 pts)	7 (10 pts)		
1.	(a) Billiard balls made from phenol-formaldehyde	(2 pts)	8 (10 pts)		
	(b) Plastic wrap		Total		
	(c) Vulcanized natural rubber				
II.	With increasing temperature, indicate the change of or does not change). (6 pts) i: Viscoelastic modulus in polystyrene ii: Resistance of Aluminum	f the following material pr	coperties (increase, decrea	ıse	

III. For steels: (2 pts)

- (a) Tempering is a process of heating the martensitic steel to gain ductility
- (b) Pearlitic steels are stronger than tempered martensite.
- (c) Martensitic steels are formed by water quenching
- (d) Bainite is stronger than fine pearlite
- IV. Which of the following are strengthening mechanisms NOT available for binary Ni-Cu alloys: (2 pts)
 - (a) precipitation hardening
 - (b) grain size strengthening
 - (c) solid-solution strengthening
 - (d) strain hardening/cold-working
- V. The mobilities of semiconductors and metals (2 pts)
 - (a) Increase with increasing temperature
 - (b) Decrease with increasing temperature
 - (c) Semiconductor mobility increases, metal mobility decreases with increasing temperature
 - (d) Exhibits no temperature dependence
- VI. Which of the following processes involve thermal activation energy (2 pts)
 - a. intrinsic conduction in semiconductors
 - b. steady state creep rate
 - c. cold work

- VII. Shown below are two creep-related graphs, both have stress as the y-axis. The x-axis (arbitrary units) is either the steady-state creep rate (creep strain per time) OR the time to failure. (4 pts).
- VIII. For lines 1&2, specify whether the x-axis is steady-state creep rate or time to failure
- IX. For lines 1&2, specify whether line 1 or line 2 is for the higher temperature
- X. For lines 3&4, specify whether the x-axis is steady-state creep rate or time to failure
- XI. For lines 3&4, specify whether line 3 or line 4 is for the higher temperature



Problem 2 Short answers (10 pt)

1.(2 pts) Plot typical (qualitative) S-N curves for steels and for non-ferrous alloys. Mark the fatigue limit and the fatigue strength on the appropriate plot.

2.(2 pts) Describe the 3-point bend test as a mean to determine mechanical properties of brittle materials

3.(3 pts) Explain (2-3 sentences) whether bending a paper clip until it breaks is an example of fatigue. If not, what is it an example of?

4.(3 Pts) Steel is described as containing (at equilibrium, at room temperature)two different types of grains, ferrite (bcc) and the one shown below:



This type of grain is referred to as ______ and consist of these phases: ______ and ______ (names other than 'iron' and 'iron carbide').

Problem 3: (10 pt) Phase Diagram

The Fe-C phase diagram is shown below:



a) Identify the equilibrium phases present at 725 °C (after cooling down from the austenite phase region) in the following steels: (6 points)

- Fe- 0.38 wt.% C :
- Fe- 0.76 wt.% C :
- Fe- 1.4 wt.% C :
- (2 pts each phase)

b) Consider 2.0 kg of a 99.6 wt% Fe–0.4 wt% C alloy that is cooled to a temperature just below the eutectoid. (i) How many kilograms of proeutectoid ferrite form? (ii) How many kilograms of eutectoid ferrite form? (4 points)

<u>Problem 4</u> (14 pts) Diffusion & Electrical Properties

Silicon (Si) is to be doped with Boron (B) such that the extrinsic semiconductor has a room temperature electrical conductivity of 0.08 $(\Omega m)^{-1}$. To achieve this, B atoms are diffused into a pure crystalline Si wafer using a heat treatment conducted at 900°C for 286.5 hours. The surface concentration of B is to be maintained at a constant level of $3.0x10^{24}$ atoms/ m^3 . The values of activation energy and pre-exponential are 3.87eV/atom and $2.4x10^{-3}m^2/\text{s}$, respectively. Si has a density of $2.33g/cm^3$, an intrinsic conductivity of $4x10^{-4}$ (Ωm)⁻¹, with $\mu_e = 0.19 m^2/\text{Vs}$. B has a density of $2.34 g/cm^3$. Assume that B atoms substitute for Si atoms and saturation is reached.

- (i.) Find the concentration of B in Si at a depth of 1.0μ m from the surface. (6pts)
- (ii.) Assuming the value from (i) to be the equilibrium concentration of B in Si, find:
 - a. The atomic % of B in the Si sample.(4pts)
 - b. The charge carrier mobility of this sample. (Hint: what is the dominant charge carrier in this extrinsic semiconductor?) (4pts)

The electrical conductivity of this sample if it was further doped with an additional $5x10^{18}$ atoms/ m^{3} B.

Problem 5. (12 pt) Mechanical Properties

(a) Copper and nickel form a binary isomorphous system. Pure copper has a tensile strength \sim 220 MPa and pure nickel has a tensile strength \sim 340 MPa. For a 50 wt% Cu and 50 wt% Ni alloy, which of the following do you expect for the tensile strength and for ductility and explain why. (4 pts)

- Tensile strength
- i. Tensile strength less than pure Cu
- ii.Tensile strength between pure Cu and pure Ni
- iii. Tensile strength higher than pure Ni

Ductility

- i. Ductility less than pure Cu
- ii. Ductility between pure Cu and pure Ni
- iii. Ductility higher than pure Ni

(b) A structure component is to be fabricated from a metal alloy with a plane-strain fracture toughness of 25 MPa-m^{1/2} and a yield strength of 860 MPa. The flaw size detection limit of the equipment is 3.0 mm. If the design stress is one half of the yield strength and Y=1.0, determine whether a critical flaw for this component is subject to detection. (8 pt)

Problem 6. (14 pt) Polymer

a. Molecular weight data for some polymer A are tabulated here. Compute (a) the number-average molecular weight (3 pts),(b) the weight-average molecular weight (3 pts). (c) If the degree of polymerization is 560 what is the repeat unit molecular weight m (3 pts).

Molecular Weight Range g/mol	<i>r</i> .	142-
15,000–30,000	$\frac{\chi_l}{0.04}$	0.01
30,000–45,000	0.07	0.04
45,000–60,000	0.16	0.11
60,000–75,000	0.26	0.24
75,000–90,000	0.24	0.27
90,000–105,000	0.12	0.16
105,000–120,000	0.08	0.12
120,000–135,000	0.03	0.05

b. (i) On a relaxation modulus (y-axis) vs temperature (x-axis) graph, clearly plot two curves for polyethylene with 30% crystallinity and 50% (2 pts), (ii) clearly mark curves and each characteristic points(3pt).

Problem 7 Composites (10pts)

A continuous and aligned fiber-reinforced composite is to be produced consisting of 30 vol% aramid fibers and 70 vol% of a polycarbonate matrix; mechanical characteristics of these two materials are as follows:

	Modulus of Elasticity [GPa (psi)]	Tensile Strength [MPa (psi)]
Aramid fiber	$131(19 \times 10^6)$	3600 (520,000)
Polycarbonate	$2.4 (3.5 \times 10^5)$	65 (9425)

Also, the stress on the polycarbonate matrix when the aramid fibers fail is 45 MPa (6500 psi). For this composite, compute the following:

(a) (5 pts) the longitudinal tensile strength, and

(b) (5pts) the longitudinal modulus of elasticity

Problem 8 (10 pts) Optical properties

A bulk CdSe p-n junction can be made into an LED emitting at 730 nm. Explain whether this material is opaque, transparent or colored in transmission. (Note: the photon energies, hv, for red and blue lights are 1.8 and 3.1 eV, respectively)

Useful equations, tables and constants:

 $N_A = 6.02 \text{ x } 10^{23} \text{ atoms/mole}$ Boltzman's constant k = 8.62 x 10⁻⁵ eV/atom-^oK Boltzman's constant R = 8.31 J/mol-ºK Electron charge $|e| = |h| = 1.602 \times 10^{-19} \text{ C}$ Planck's constant. $h = 4.13 \times 10^{-15} \text{ eV-s}$ Speed of light in vacuum, $c = 3.0 \times 10^8 \text{ m/s}$

 $10^9 = giga$ $10^6 = mega$ 1500 Liquid 1453% $10^{3} = kilo$ 1400 emperature (°C) Liquidus $10^{-2} = \text{centi}$ 1300 $10^{-3} = milli$ 1200 $10^{-6} = micro$ 1100 O Zn S S 1085 $10^{-9} = nano$ 1000

 $10^{-12} = pico$



 $a = 2R\sqrt{2} \qquad a = \frac{4R}{\sqrt{3}} \qquad APF = \frac{V_s}{V_c}$ $\rho = \frac{nA}{V_c N_A} \qquad N_v = N_e \exp\left(-\frac{Q_v}{kT}\right) \qquad \sigma_T = \sigma(1+\varepsilon)$ $\sigma_T = \sigma(1+\varepsilon)$ $\varepsilon_{\tau} = \ln(1 + \varepsilon)$ $\sigma = \frac{F}{A_o}$ $\varepsilon = \frac{l - l_o}{l_o} = \frac{\Delta l}{l_o}$ $\sigma = E\varepsilon$ $\tau = G\gamma$ $v = -\frac{\varepsilon_x}{\varepsilon_z} = -\frac{\varepsilon_y}{\varepsilon_z} \qquad E = 2G(1+v) \qquad \sigma_m = 2\sigma_o \left(\frac{a}{\Omega}\right)^{1/2} \qquad \sigma_c = \left(\frac{2E\gamma_s}{\pi a}\right)^{1/2}$ $\%EL = \left(\frac{l_f - l_o}{l_o}\right) \times 100 \qquad U_r = \frac{1}{2}\sigma_y \varepsilon_y = \frac{\sigma_y^2}{2E} \qquad K_c = Y\sigma\sqrt{\pi a} \qquad K_{lc} = Y\sigma\sqrt{\pi a}$ $\dot{\varepsilon}_s = K\sigma^n \exp\left(-\frac{Q_c}{RT}\right)$ $\frac{C_x - C_o}{C - C} = 1 - erf\left(\frac{x}{2\sqrt{Dt}}\right)$ $D = D_o \exp\left(-\frac{Q_d}{RT}\right)$

C = O/VE = V/l $P = \Sigma a d / V_c$ p=qd $C = \varepsilon_0 A/l$ (vacuum) $C = \varepsilon A/l$ (dielectric material) $\varepsilon_r = \varepsilon/\varepsilon_o$ $\eta \approx (\varepsilon_r)^{1/2}$ index of refraction for non-magnetic materials $D = \varepsilon E = \varepsilon_0 E + P$ (dielectric material) $D_0 = \varepsilon_0 E$ (vacuum)

$$\begin{split} \sigma &= 1/\rho & \text{Metals: } \sigma = n|e|\mu_e & \text{Semiconductors: } \sigma_{total} = n|e|\mu_e + p|e|\mu_h \\ n_i &= n_o exp \ (-Eg/2kT), \ p_i = p_o exp \ (-Eg/2kT) & \sigma \approx \sigma_o exp \ (-Eg/2kT), \ p_o = n_o \\ n &\approx n_o exp (-\Delta E/kT), \ p &\approx p_o exp (-\Delta E/kT) & \sigma \approx \sigma_o exp \ (-\Delta E/kT) & E = h\nu = hc/\lambda \end{split}$$

$$\overline{M}_{n} = \sum x_{i}M_{i} \quad \overline{M}_{w} = \sum w_{i}M_{i} \quad DP_{n} = \sum x_{i}n_{i} = \frac{\overline{M}_{n}}{\overline{m}}, \quad DP_{w} = \sum w_{i}n_{i} = \frac{\overline{M}_{w}}{\overline{m}}, \quad \overline{m} = \sum f_{i}m_{i} \quad E_{r}(t) = \frac{\sigma(t)}{\varepsilon_{o}}$$

$$\ln c = \frac{\sigma *_{f}}{2\tau_{c}} \quad E_{c} = E_{m} V_{m} + E_{f}V_{f}, \quad \frac{1}{E_{ct}} = \frac{V_{m}}{E_{m}} + \frac{V_{f}}{E_{f}}$$

$$(l > 15l_{c}): \sigma^{*}c = \sigma^{*}fV_{f} + \sigma^{*}m(1 - V_{f}); \quad (l_{c} < l < 15l_{c}): \sigma^{*}c = \sigma^{*}fV_{f}(1 - l_{c}/2l) + \sigma^{*}m(1 - V_{f}),$$

$$(l < l_{c}) \sigma^{*}c = (l\tau_{c}/d) V_{f} + \sigma^{*}m(1 - V_{f})$$

z	erf(z)	z	erf(z)	z	erf(z)
0	0	0.55	0.5633	1.3	0.9340
0.025	0.0282	0.60	0.6039	1.4	0.9523
0.05	0.0564	0.65	0.6420	1.5	0.9661
0.10	0.1125	0.70	0.6778	1.6	0.9763
0.15	0.1680	0.75	0.7112	1.7	0.9838
0.20	0.2227	0.80	0.7421	1.8	0.9891
0.25	0.2763	0.85	0.7707	1.9	0.9928
0.30	0.3286	0.90	0.7970	2.0	0.9953
0.35	0.3794	0.95	0.8209	2.2	0.9981
0.40	0.4284	1.0	0.8427	2.4	0.9993
0.45	0.4755	1.1	0.8802	2.6	0.9998
0.50	0.5205	1.2	0.9103	2.8	0.9999



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